

## Electronic Patent Application Fee Transmittal

Application Number:	10580036			
Filing Date:	19-May-2006			
Title of Invention:	Plasma processing method and plasma processing apparatus			
First Named Inventor/Applicant Name:	Yasuo Kobayashi			
Filer:	Marvin Jay Spivak/Yuriko Stankich			
Attorney Docket Number:	291327US26PCT			
Filed as Large Entity				
<b>U.S. National Stage under 35 USC 371 Filing Fees</b>				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
<b>Post-Allowance-and-Post-Issuance:</b>				
<b>Extension-of-Time:</b>				
Extension - 2 months with \$0 paid	1252	1	490	490

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Miscellaneous:</b>				
<b>Total in USD (\$)</b>				<b>490</b>